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RRAM Variability and its Mitigation Schemes

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Abstract—Emerging technologies such as RRAMs are attracting significant attention, due to their tempting characteristics such as high scalability, CMOS compatibility and non-volatility to replace the current conventional memories. However, critical causes of hardware reliability failures (such as process variation due to their nano-scale structure) have gained considerable importance for having acceptable memory yields. Such vulnerabilities make it essential to investigate new robust design strategies at the circuit and system level. In this paper we have first reviewed the RRAM variability phenomenon and the variation tolerant techniques at the circuit level. Then we have analyzed the impact of variability on memory reliability and have proposed a variation-monitoring circuit that discerns the reliable memory cells affected by process variability.

Index Terms—RRAM; Reliability; Process Variability; Mitigation; Emerging Memory; Resistive Memory

I. INTRODUCTION

As Moore's law approaching its ultimate stages, the research for alternative memory technologies has been accelerated to explore the best candidates for future memory systems. One of these candidates is the resistive memory, including different device types, classified by their switching mechanisms. Among them, the two terminal devices that hold the information in the resistance between terminals, such as Phase Change Random Access Memory (PCRAM), Spin Transfer Torque RAM (STT-RAM) and Redox Memory (RRAM) are the most important ones.

In PCRAM the resistivity can switch between high and low states, because of resistance difference between the amorphous and the crystalline states of chalcogenide glass [1]. STT-RAM can have high or low resistance states in correspondence to its magnetic tunnel junction [2]. RRAM functions based on the change of resistance value on a Metal-Insulator-Metal (MIM) structure [3]. Its resistance varies because of ion migration inside the structure along with some redox processes including electrode/insulator material.

The RRAM has multiple advantages over STT-MRAM and PCRAM such as: 1) It can be better scaled (down to few nm) because of its ion based switching mechanism [3]; 2) It is possible to make a memory cell with a single RRAM, while the other two need a select device [4]; 3) It is compatible with monolithic 3D integration and crossbar architecture to make high density memory [5]; 4) It has better endurance than PCM and larger on/off ratio than STT-MRAM [6].

The RRAM itself has been categorized to four types based on its switching mechanism [6]: 1) Electrochemical Metallization Bridge Memory (EMB), 2) Metal Oxide Bipolar Filamentary, 3) Metal Oxide Unipolar Filamentary and 4) Metal Oxide Bipolar Non-Filamentary. Among them, the second type has shown promising characteristics and is the most popular RRAM in research and commercial prototyping; for this it is chosen for study in this paper as well. However, in spite of all interesting RRAM features, various reliability concerns such as the process variability are reported in literature as a challenging factor.

With the device dimensions scale down to the nanoscale regime, the device variability has taken a crucial relevance into the devices behavior, and consequently on memory reliability and performance. These process fluctuations have become also relevant in RRAM [7], as it is also designed in nano-scale sizes for high density embedded memory applications [8]. Therefore, this challenge has motivated the develop of approaches and techniques at various system levels, such as improving the device material, designing resilient circuits and architectures to somehow avoid or mitigate the variability effect. While improving the device variability is mostly a manufacturing matter, the key tool for improving the yield is considering variation-tolerant circuits, which is the main focus of this paper.

Conventionally memories use peripheral or assist circuits to improve the chip-level reliability. These circuits are mainly utilized to mitigate the existing manufacturing reliability concerns such as the time-zero process variability. However, with time travel the reliability characteristics of the device can shift and a cell which was considered reliable before may not be reliable anymore. This is very relevant in RRAM devices which are affected not only by the process variation but also by endurance degradation. It can cause drift in high and low resistance values, making the sensing difficult in the cell's read process. Therefore a monitoring technique is needed which can track the high to low resistance ratio of the RRAM device and to recognize the reliable cells from the possible non-reliable ones. Regarding this, we present a monitoring scheme which can correctly measure temporal variations in RRAM memory array.

This paper is organized as following: Section II studies the main origins causing RRAM variability, Section III reviews some of the techniques to mitigate the variability at circuit

level; in Section IV we analyze the impact of variability in the reliability of the memory; Section V demonstrates our proposed technique to monitor process variability in RRAM memory; and finally Section VI concludes the paper.

II. RRAM VARIABILITY

One of the major sources of unreliability in RRAM memory design is existence of resistance fluctuations in its nominal Low Resistance State (LRS) and High Resistance State (HRS) values [7]. This phenomenon can affect the robustness of the memory operation and reduces the yield. RRAM devices suffer from two types of variation: cycle-to-cycle and device-to-device. In this paper we will only consider the last one, firstly because it has wider distribution than cycle-to-cycle deviation, and second because unlike cycle-to-cycle which is more related to the device stability and its constructing material the device-to-device variation characterizes the uniformity of memory array and can be treated/mitigated at circuit level.

Figure 1.a shows an example for RRAM device-to-device variability [9] at its LRS and HRS. Moreover, Figure 1.b points out the fluctuation of HRS and LRS in resistance switching.

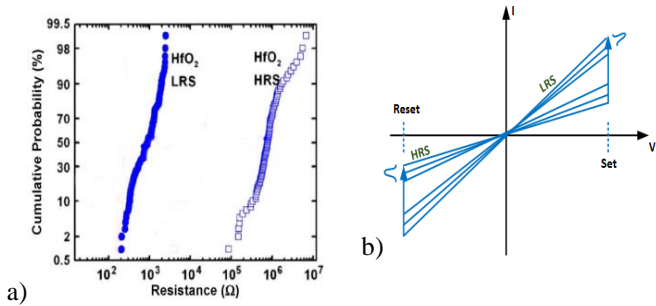


Figure. 1. a) Statistical distribution of resistances in HRS and LRS for 100 sweep cycles adapted from [9]; b) RRAM I-V characteristic with resistance variability switching.

In order to better understand the origins behind the RRAM variability it is worth to consider the RRAM switching mechanism. The RRAM switching mechanism is based on Conductive Filamentary (CF) mechanism where the existing defects (such as oxygen vacancies) result in formation and disruption of CF and change of resistance from LRS to HRS and vice versa [10]. In these devices first an electroforming process with a voltage higher than the normal operation is applied to the device to construct an initial filament between top and bottom electrodes. The first formed filament does not connect the top and bottom electrodes and the device is in its HRS infant mode. To switch the device to LRS, a positive voltage is applied to the top electrode. This will pull out the oxygen ions from the lattice and generate oxygen vacancies which will extend the filament and switch the RRAM from HRS to LRS (SET). To switch the RRAM from LRS to HRS (RESET) a reverse voltage is applied which will bring back the oxygen ions to the lattice and then they will re-combine with the oxygen vacancies and rupture the filament toward

HRS. All these processes of electroforming, SET and RESET if not controlled well can cause considerable variability. Now, here we will explain the main sources of fluctuations in RRAMs.

A. Electroforming

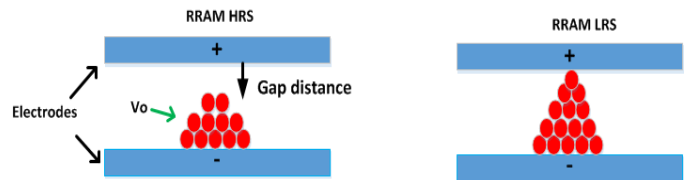
In the forming process generally a quasi-DC sweep on the bit-line up to 3.5V with a step voltage equal to 0.025V is applied. Special current control of the device is needed (usually by a select device) to avoid hard breakdown. However there always exist some deviation in the applied forming voltage that will consequently cause distributions of RRAM'S LRS and HRS [11].

B. Fluctuation in CF radius or number of CFs

The stochastic nature of ion migration will cause different CF shapes, sizes (specifically in the radius) and number of CFs [12]. As RRAM resistance value strongly depends on the CF structure, any non-uniformity of CF will be the origin of variability.

C. Tunneling gap distance variation

The distance between the created filament and the top electrode is called the gap distance. Any variation in this parameter can affect the tunneling current and would impose resistance variation in RRAM (mainly HRS variation) [12]. It is noted that the HRS variation (ranging from 5x to 100x) is generally larger than the LRS variation (ranging from 2x to 10x) because of its exponential dependence of the tunneling current affected by gap distance [3]. Figure 2 shows an example for CF in HRS and LRS mode.



Conductive Filamentary Mechanism

Figure 2. RRAM filament in LRS and HRS

Beside these intrinsic RRAM variability sources, the operating parameters can also affect the device variability. For instance lower V_{SET} value and pulse width will increase the LRS variation. Increasing temperature also results in higher resistance variation mainly because of retention loss [7]. Furthermore, aging will also deteriorate variation during the cycles, making it essential to take into account the time-dependent parameters in device variability.

The RRAM variability imposes severe concerns into the reliable operation of the memory array that needs to be taken care and mitigated inside the memory.

III. VARIABILITY MITIGATION

There are different methodologies to improve or mitigate the variability of RRAM devices. Figure 3 shows these approaches classified in three groups of device engineering,

optimizing operation and circuit approaches. One of the conventional methods is based on material engineering that tries to decrease the device resistance fluctuations by utilizing enhanced material or interfaces [3]. Another variability-mitigating approach is to use optimized programming (SET/RESET) methods that can constrain the distribution of LRS and HRS states [7]. Ultimately the key final approach which is mainly considered in this paper is based on circuit design innovations inside the RRAM memory array or its CMOS peripherals, to suppress the variability effect. In the following the circuit-based techniques are presented and described.

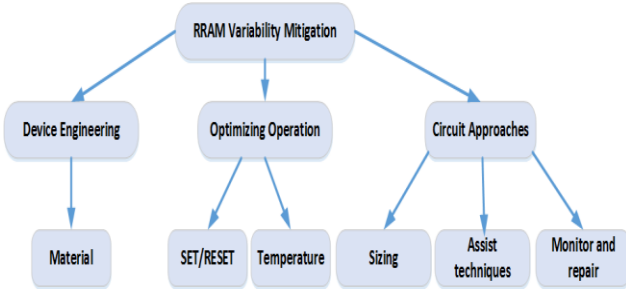


Figure 3. RRAM variability mitigation techniques

A. Sizing

The concept of RRAM sizing is different from the conventional transistor sizing as the device contains two terminals and does not have an active channel. It has been shown that the RRAM memory cell can be constructed by two parallel RRAMs to mitigate the variability fallout [13]. This technique has been relevant by using the concept of putting the resistors in parallel and consequently the overall resistance value can be more variation-tolerant, though it can impact the performance and area overhead of the memory array.

B. Circuit Assist Techniques

Because of the existing variations in the LRS and HRS and also the variations in reference cells; the read process can become incorrect. Therefore, it is necessary to design sensing circuits/approaches that can tolerate these fluctuations. One of such techniques is to reduce the V_{Ref} or I_{Ref} distribution to ensure a correct read process inside the RRAM memory array [14]. This can be done by a parallel-series reference cell (PSRC) scheme that narrows the I_{Ref} distribution and reduces σI_{Ref} against the resistance variation [20]. Figure 4 shows the concept for the failure and clarifies the fact that a narrowed I_{Ref} distribution can help to improve the read margin.

Another approach to improve the read margin in presence of process variability can be based on utilizing an adaptive reference current scheme to feed the current mode sense amplifier [15]. The adaptive reference current scheme can detect the spatial resistance distribution and generate the optimum reference current for reliable read operation. Figure 5 shows the adaptive reference current scheme to make the correct read operation in a variability-aware RRAM memory.

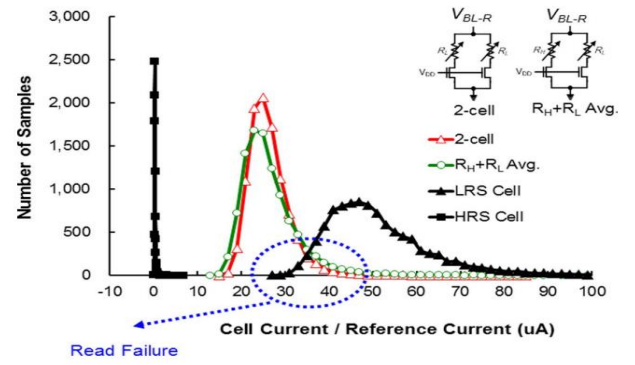


Figure 4. Narrowing I_{Ref} is a solution to improve the read margin adapted from [14]

In addition to these approaches there are also other circuit assist techniques implemented at the periphery of the RRAM array to enlarge the memory read window and enhance the RRAM memory yield [16]. Such approaches aim for advanced read/write mechanisms to tolerate the existing process variability inside the RRAM arrays.

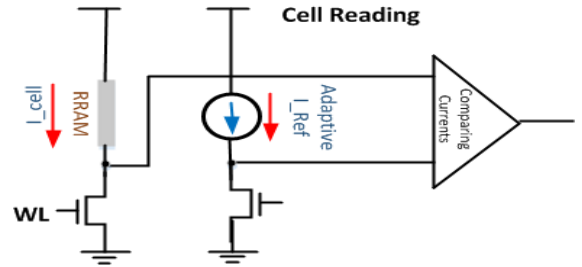


Figure 5. Adaptive reference current to improve RRAM Read margin [15]

The existing fluctuation in the resistance distribution of RRAM cells motivates the design for monitoring techniques to measure the HRS to LRS resistance ratio to guarantee a reliable memory operation. For this a monitoring techniques which can measure the HRS to LRS ratio and analyze the reliability of RRAM device is presented in section V.

IV. IMPACT OF RRAM VARIABILITY IN RELIABILITY

The correct operation of memory depends on the precise Read/Write process, nevertheless the existing variability can disturb them and reduce the memory yield [17].

One of the techniques for writing the RRAM devices is called the preset writing in which the selected RRAM is first reset to the LRS state and then by applying an appropriate pulse it is switched to the desired state [18]. Generally a squared pulse voltage with a specific width is applied to the device to change the state of RRAM. However, because of existing process variability in the RRAM array, the resistance state can be in its tail points (a very low LRS or a very high HRS) and therefore the voltage pulse would not be sufficient to switch the RRAM to the correct state. This may lead to a memory fault and can be detected with special March tests inside the RRAM array [19].

Generally there are two commonly used read approaches in RRAM memory arrays: Voltage mode and Current mode sensing, where in both of them a sensed voltage/current (V_{cell}/I_{cell}) is compared with a reference voltage/current (V_{Ref}/I_{Ref} generated using reference cells) and the state of the device is recognized. Depending on the RRAM if it is in LRS or HRS state the current/voltage would differ and a '0' or '1' is read from the cell.

By considering normal distributions for LRS, HRS and the Reference resistance it is possible to analyze the probability of failure in the read procedure of RRAM array. The P_e is a variable, which determines the likelihood of an incorrect read in the RRAM memory cell in function of a reference resistance value (Ref), with which the reference resistance is compared. The P_e graph is calculated in 10000 cases while considering a reference point in resistance value (in which below Ref it is expected to be in LRS state and for higher than Ref the HRS state is anticipated). In this work the HRS and LRS characteristics are obtained from experimental results in the literature such as in [20,21]: $\mu(LRS)=10K\Omega$, $\mu(HRS)=100K\Omega$ and $\sigma(LRS)=20\%$ and $\sigma(HRS)=20\%$ of the mean value. Figure 6 shows the probability of failure for the normal distribution of HRS and LRS and when considering that the Reference resistance value is a random value from another normal distribution $\mu(Ref)=\mu(HRS)/2+\mu(LRS)/2$ and $\sigma(Ref)=(\sigma(LRS)/2)^2+(\sigma(HRS)/2)^2$.

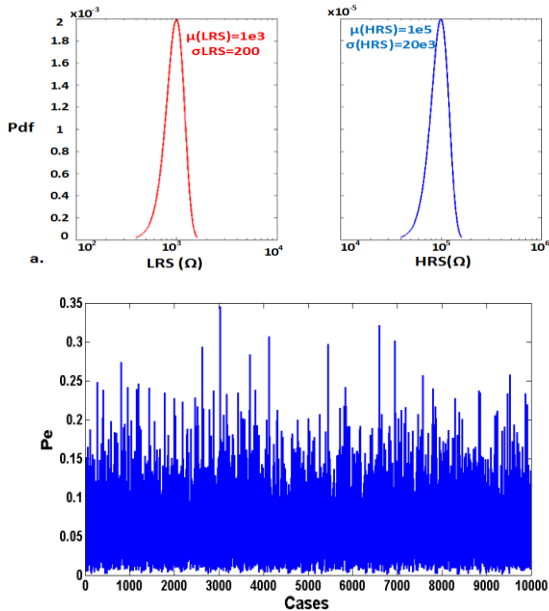


Figure 6. The HRS and LRS normal distributions along with probability of error in RRAM read process

It is observed from Figure 6 that the read process cannot be always error free ($p_e > 0$ in some cases) and for instance in our analysis with respective values, the probability of error can be around 20-25%. Therefore, the wide resistance distribution of RRAM cells can impose low read yields and can reduce the device lifetime [22]; consequently it is needed to design variability tolerant circuits, and techniques to monitor the

variability in the memory array, such as the one presented in the next section.

V. VARIABILITY MONITORING TECHNIQUE

In order to show the mechanism of our monitoring methodology, first the RRAM memory operation is described in brief. Then the monitoring circuit is presented and the simulation results according to the variability monitoring are demonstrated.

A. 1T1R Memory Array Structure

RRAM memory systems are commonly organized in a matrix-like structure called crossbar. The storage cell in the crossbar can be built with only one RRAM device (1R cell), but due to the well-known problem of sneak-path a select device such as a transistor is utilized in constructing the memory cell (1T1R) [23]. Therefore, the 1T1R cell generally consists of an NMOS transistor and a resistive switching device. In this structure the RRAM current is correctly controlled through the array and each device is turned 'on' or 'off' based on the row address in the matrix. Figure 7 presents an example 2x2 RRAM memory constructed with 1T1R as storage cells. Note that the square boxes in this figure are multiplexers, which govern the appropriate voltage or current to be applied to the cells.

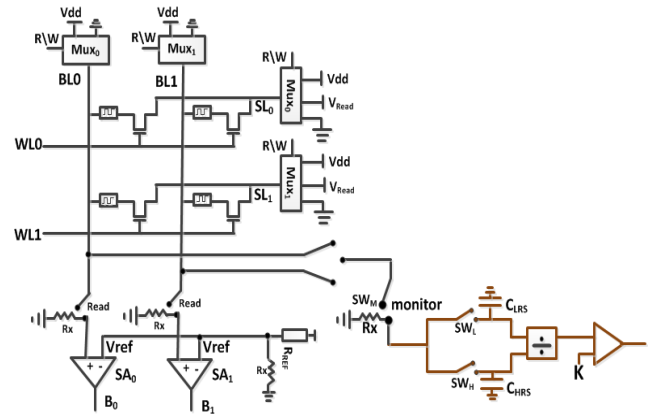


Figure 3. A 2x2 RRAM memory with peripherals along with the variability monitoring circuit

Each 1T1R cell can be written and read by applying the appropriate signals through the bit-line (BL), word-line (WL) and the select line (SL). To write '1' in the cell (also called SET process), first the corresponding WL is activated in the array, and next while the SL is grounded an appropriate voltage is applied at the BL (V_{DD}). Changing the state of RRAM from LRS to HRS, is called the RESET process, and it is equivalent to writing a '0' in the cell. For this process the WL is again activated, when a proper voltage (V_{DD}) is applied at the SL, and while the corresponding BL is grounded, the other BLs in the block are all in high impedance mode.

To read the RRAM device using the voltage sensing mode a V_{Read} voltage (lower than the write voltage) is applied to the corresponding 1T1R cell, and the BL voltage (a voltage division of the read voltage through the RRAM resistance and the resistor R_x), will be detected through the comparator giving the state of RRAM and the bit-cell. A reference cell, consisting of a reference resistance (R_{Ref}), is used to generate a reference voltage to be compared in the comparator. A resistive device in LRS state will produce a higher voltage in comparison with one at HRS mode. It is important that the read voltage (V_{Read}) be much lower than the write voltage V_{DD} in order not to modify the state of RRAM in the read operation. Also note that in this work the read mode based on voltage is chosen, the reason is controlling the applied voltage to the RRAM cell is easier and also the model which we will later use for circuit simulation works better in voltage mode.

To implement the variability-monitoring mechanism, it is considered that the memory can benefit from idle cycles during its operation and the granularity for monitoring scenario in the array is row-by-row in each phase because it is easier to control the monitoring flow rather than in the column-by-column approach. Also the area overhead can be reduced if the monitoring granularity is chosen to be at row level and not in column level, because less multiplexer would be needed. Here, a monitoring technique based on analyzing the process variability of the RRAM cells during the memory lifetime is demonstrated. This monitoring approach can be applied to the cells, row-by-row one-by-one and can evaluate the relation between HRS and LRS for a robust memory operation. In fact the monitoring includes a set of write and read operations, where in each step resistance state is monitored through the monitoring circuits.

Figure 7 shows the monitoring circuit attached to the 2x2 1T1R memory array. This monitoring circuit is constructed with some switches (SW_M ; SW_L ; SW_H) to control the correct passing current, two capacitors (C_{LRS} , C_{HRS}) to store respecting voltages to LRS and HRS, a divisor to calculate the ratio between HRS and LRS, and a comparator to compare the division result with the design value of $K = \text{HRS} \div \text{LRS}$. The cells will undergo the monitoring phase one-by-one and their reliability will be analyzed.

B. Simulation of 1T1R Monitoring Circuit

In order to perform the circuit simulations, this work uses the resistive switching (RRAM) Verilog model designed by Stanford University [24]. This model is designed for bipolar metal oxide RRAM devices based on conductive filament switching concept and has no limitations on the size of RRAM cell. We have considered all the default sizes in the model proposed by authors such as the cell size, which is equal to $10 \times 10 \text{ nm}^2$. The monitoring circuit shown in Figure 7 is simulated by HSPICE for monitoring one RRAM cell, and Figure 8 depicts the circuit simulation obtained results for one RRAM cell.

The simulation is transient and contains first writing a '0' inside the cell assuming LRS as an initial state. In order to write '0' inside the cell without interference with monitoring section we have considered some switches in the monitoring

path. At this phase, the switches are as following $SW_M = \text{open}$ to isolate the monitoring circuits and also $SW_L, SW_H = \text{open}$. At the moment of writing '0' the RRAM current goes to almost zero, because the resistance state is switched from LRS to HRS and no current can flow inside the device. Then, in the monitoring phase, we are interested to measure the value of HRS. This is done by applying appropriate voltage from the source-line and to close two of the switches in the circuit ($SW_M = \text{close}, SW_H = \text{close}$), while one switch is kept open $SW_L = \text{open}$ for further monitoring steps. Figure 8 shows in detail that the corresponding voltage to HRS is stored through our monitoring circuit and capacitor (C_{HRS}), such that the V_{CHRS} is equal to the voltage divided between R_x and HRS.

Next, the objective would be to measure the corresponding voltage according to LRS of the RRAM. Therefore, it is needed to write '1' inside the cell. Again, the isolating switches should be open ($SW_M, SW_L, SW_H = \text{open}$) and a transient HSPICE simulation is done. Figure 8 shows how the RRAM current goes up to 300uA, due to its switching from HRS to LRS, in which more current can pass through the device. After writing '1' it is time to monitor the LRS status of the device by applying the appropriate voltage from the source-line and closing two switches such as ($SW_M = \text{close}, SW_L = \text{close}$) and keeping one switch open ($SW_H = \text{open}$) for proper monitoring. Then, accordingly the other capacitor in monitoring circuit (C_{LRS}), V_{CLRS} holds the voltage divided between R_x and LRS. After these, the monitoring phase continues with dividing these values and finding out their ratio that is $\{\text{HRS} \div \text{LRS}\}$ (around 23 in this example for a fresh RRAM cell in Stanford model). Note that, in this case the value of R_x is important and can have significant impact on the measurement if it is chosen big. In the phase of monitoring if the $\{\text{HRS} \div \text{LRS}\}$ value is acceptable (for instance in this specific example $K > 23$) the cell is recognized as a healthy cell and if not it is identified as a weak, making the memory repairing techniques essential.

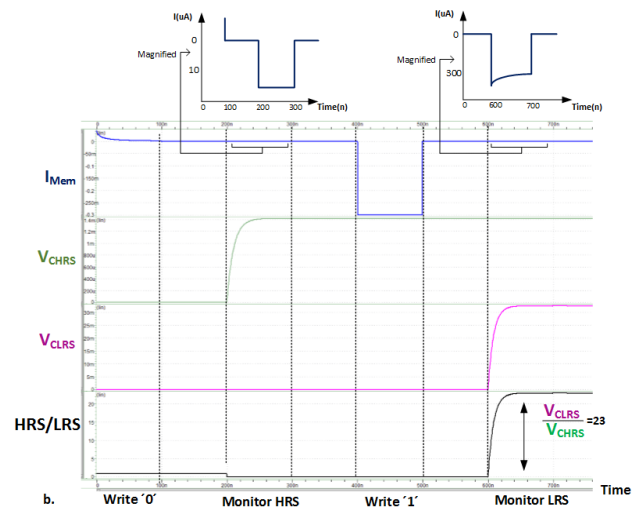


Figure 4. HSPICE circuit simulation using Stanford model to monitor variability by measuring HRS to LRS ratio

VI. CONCLUSIONS

In this work RRAM reliability was analyzed from process variability point of view. The main sources of RRAM variability were studied, then circuit techniques were reviewed to mitigate the variability effect and improve the yield of RRAM memory array. Next, the process variability impact on RRAM memory operation was analyzed and it was shown that there is a big impact on performing a reliable read operation of the memory cell. Finally, a variability-monitoring scheme was presented to measure the on/off ratio inside the RRAM memory array and to monitor the fluctuations between the HRS and LRS. This monitoring technique can help to differentiate the reliable RRAM memory cells from the weak ones.

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